

**UCF MATERIALS CHARACTERIZATION FACILITY
CORPORATE FEE SCHEDULE 2024-2025**

| <u>Equipment</u> | <u>Hourly Rate</u> |
|---|---------------------------|
| Scanning Electron Microscopy (SEM) | |
| Zeiss Ultra-55 | 200 |
| Transmission Electron Microscopy (TEM) | |
| Jeol JEM-1-11 | 300 |
| Tecnai F30 | 450 |
| Focused Ion Beam (FIB) | |
| FEI 200 TEM | 250 |
| Zeiss FIB Crossbeam | 350 |
| X-Ray Diffraction (XRD) | |
| XRD -- GN (Panalytical) | 150 |
| XRD -- TF (Panalytical) | 200 |
| XRD -- EC (Panalytical) | 200 |
| Secondary Ion Mass Spectrometry (SIMS) | |
| Cameca IMS-3F | 300 |
| PHI Adept | 300 |
| Miscellaneous | |
| XPS Escalab 250Xi | 300 |
| X-Ray Fluorescence Spectrometer (XRF) (Panalytical) | 150 |
| Sputter Coater (Quoram) | 150 |
| Other Instruments | |
| Critical Point Dryer | 75 |
| Ultra Microtom (Leica) | 75 |
| Leica Trimmer | 75 |
| Plasma Cleaner | 75 |
| Metallurgical Microscope | 75 |
| MicroRaman Spectroscopy | 75 |
| Profilometer | 75 |
| Reichert Optical Microscope | 75 |